

8. Tanner FX (2004) Development and Validation of a Cascade Atomization and Drop Breakup Model for High-Velocity Dense Sprays. *Atomization Sprays* 14(3):211–242
9. Lang RJ (1962) Ultrasonic Atomization of Liquids. *J Acoust Soc Am* 34:6
10. Shi WT, Goodridge CL, Lathrop DP (1997) Beraking waves: bifurcations leading to a singular wave state. *Phys Rev E* 56(4):4157–4161
11. Piriz AR et al (2005) Rayleigh-Taylor instability in elastic solids. *Phys Rev E* 72(056313):1–10
12. Forde G, Friend J, Williamson T (2006) Straightforward biodegradable nanoparticle generation through megahertz-order ultrasonic atomization. *Appl Phys Lett* 89:064105
13. Shiokawa S et al (1989) Liquid streaming and droplet formation caused by leaky Rayleigh waves. In: *IEEE Ultrasonics Symposium*. IEEE, Montreal
14. Percin G, Khuri-Yakub BT (2003) Piezoelectric droplet ejector for ink-jet printing of fluids and solid particles. *Rev Sci Instrum* 74(2):1120–1127
15. Okuno T (2006) Inkjet Print Head and Manufacturing Method Thereof, U.S.P. Office. 2006, Konica Minolta Holdings, Ltd.: United States, US2006/0017778, p 21

Piezoelectric Micro/Nanoliter Droplet Dispenser

► [Piezoelectric Microdispenser](#)

Piezoelectric Pumps

► [Piezoelectric Valves](#)

Piezoelectric Valves

JAMES FRIEND, LESLIE YEO
 MicroNanophysics Research Laboratory, Monash
 University, Clayton, VIC, Australia
james.friend@eng.monash.edu.au,
leslie.yeo@eng.monash.edu.au

Synonyms

Microvalve; Piezoelectric pumps; No-moving-part valves

Definition

Structures that regulate the flow of fluids using piezoelectric materials, either composed of active regulation through deflection of a structure to block or allow passage of the fluid using electrically-driven piezoelectric elements, or as a piezoelectric pump in combination with mechanical or passive diffuser valves.

Overview

Active piezoelectric valves offer a unique combination of large closing forces – hundreds to thousands of new-

tons – against fluid loads and small displacements measured in the tens of microns. Such valves may be designed to close or open upon the application of an electric field to the piezoelectric material, and offer flow rates from nearly arbitrarily low amounts to tens of liters per minute for gases, water, and similar fluids [1]. Given the limited strain, 0.1% or less, available from typical high-performance piezoelectric ceramic materials, a majority of the research and development effort has been in amplifying this strain to permit efficient valving action. Flap or cantilever valves seated across an orifice actuated as a piezoelectric ► [bimorph](#) or ► [unimorph](#) or ball or grooved structures seated against an orifice and moved using a large-displacement ► [linear multilayer piezoelectric actuator](#) is typical of this approach.

Passive piezoelectric valves function in an entirely different manner, though they also make use of piezoelectric bimorph or unimorph structures. Forming one side of a small fluid chamber, or ► [Helmholtz cavity](#), the piezoelectric element can excite chamber resonances when driven at appropriate frequencies via an oscillatory electric field, usually from 10 Hz to 100 kHz depending on the device dimensions and fluid. With two or more orifices connecting the chamber to the outside, fluid may be passed into and out of the chamber; by using orifices with different shapes the flow direction may be regulated without requiring a mechanical blockage of the flow [2] or moving parts. Though these configurations are effective as pumps [3], they also can serve as valves for applications where some leakage is tolerable, or where ball or flap valves may be used as passive mechanical restrictions on the orifices to augment the sealing action and improve performance.

Cross References

- [Piezoelectric Microdispenser](#)
- [Piezoelectric Materials for Microfluidics](#)

References

1. Oh K, Ahn C (2006) A review of microvalves. *J Micromech Microeng* 16:13–39
2. Izzo I, Accoto D, Menciassi A, Schmitt L, Dario P (2007) Modeling and experimental validation of a piezoelectric micropump with novel no-moving-part valves. *Sens Actuators A* 133(1):128–140
3. Laser D, Santiago J (2004) A review of micropumps. *J Micromech Microeng* 14(6):35–64

pL

► [Picoliter Flow Calibration](#)